SD - Silicon Detector EM Calorimetry



SD (Silicon Detector)

- Conceived as a high performance detector for NLC
- Reasonably uncompromised performance
- But
- Constrained & Rational cost
- We accept the notion that excellent energy flow calorimetry is required, and explore optimization of a Tungsten-Silicon EMCal...

Silicon Detector EM Calorimetry



Scale of EMCal & Vertex Detector



Silicon Tungsten EMCal

- Figure of merit something like BR^2/σ , where σ is the rms sum of Moliere radius of the calorimeter and the pixel size.
 - Maintain the great Moliere radius of tungsten (9 mm) by minimizing the gaps between ~2.5 mm tungsten plates. Dilution is (1+Rgap/Rw)
 - Could a layer of silicon/support/readout etc fit in a 2.5 mm gap? Even less?? 1.5 mm goal??
- Requires *aggressive* electronic-mechanical integration!

EMCal, continued

- Diode pixels between 5 10 mm square on largest hexagon fitting in largest available wafer. (6" available now - 300 mm when??) Consider µ tracking as well as E flow in picking pixel dimension.
- Develop readout electronics of preamplification through digitization, zero suppression and IO on bump bonded chip. Upgrade would be full integration of readout on detector wafer. (R&D opportunity!)
- Optimize shaping time for small diode capacitance. Probably too long for significant bunch localization within train. But some detector element needs good time resolution!!!

Channel Counts [Forget Them!!]

- We are used to pixel counts in CCD's ...
 - 3x10⁸ last time, 1x10⁹ this time, no problem
- Silicon Strip Tracker ~5x10⁶ strips (channels??)
- EMCal ~5x10⁷ pixels (channels??)
- Don't even think about multiplying channels by O(\$10).....
- Must solve the cluster technology challenges.

Structure

Calorimeter Layer





Pixels on 6" Wafer



6 inch (152mm) WAFER

1,027 (5mm) CELLS

Zoom to Readout Chip

Center Distribution Chip



65 Columns @ 100 microns 17 Rows @ 400 microns 1,040 Points 7mm SQ

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	2	4	6	8		I
1					10	mm



Cross Section



Signal Collection from m² board



CONCENTRATOR CHIP

Preamplifier Architecture

- Charge amplifier and shaper followed by two amplifiers with gains G1,G2 and sample & holds.
- Comparator logic to select appropriate range
- Mux and 12 bit ADC



Noise and Muons

- Assume 300 μ (400-500 μ possible) effective e⁻ collection at 80 e⁻/μ. signal ~ 24000 e⁻.
- Assuming diode capacitance of 0.3 pf/mm², and amplifier noise of 20e⁻/pf+200e⁻ - noise ~400 e⁻ S/N ~60, plenty good!
- Pick S/N of 7 (Figure) for minimum performance.



Plausible Resolution Criteria

- Spread the 0.6% muon σ into several bins, with enough range for MIP counting to a few.
- Preliminary Monte Carlo indicates peak ionizing track density from a high energy shower to be 2200 μ equivalent. (5 x 10⁷ e⁻ = 8 pC.)
- Do not degrade resolution of calorimeter! Energy resolution of a sampling calorimeter with 2/3 X_0 plates will not exceed 12%/JE. Say this peak should be spread over 5 bins, and take no credit for multiple sampling.
- Relaxation of these requirements now being studied with EGS.

Required Resolution



- High Res Bin Width=1000 e⁻, Emax=37 GeV, Mips=170
- Low Res Bin Width=13200 e⁻,Emax=512 GeV,Mips=2325

Technical Issues

- Assuming integrator full scale voltage of around 1
 V, feedback (and calibration) capacitors need to
 be ~10 pF. This is large for an integrated
 capacitor, but doable with substantial real estate.
- Plus is that this makes the bump bond pitch easy!

Thermal Management

- Cooling is a fundamental problem: GLAST system is ~2 mW/channel. Assume 1000 pixels/wafer and power pulsing duty factor for NLC of 10^{-3} (10 μ sec @120 Hz), for 2 mW average power.
- Assume fixed temperature heat sink (water cooling) at outer edge of an octant, and conduction through a thick (6 oz) copper ground plane in the G10 motherboard.
- ∆T~1°C.
- This is fine, but it sure doesn't work without power pulsing!!! Holding the power down while maintaining the noise/resolution is a serious engineering challenge.

Plans

- We (Oregon and SLAC) plan to develop this design in more detail and build prototype wafers and chips.
- Test detectors in 5 Tesla field.
- If successful, develop board level chip.
- Build 1 wafer wide by about 25 X_0 deep calorimeter for test beam.